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PATENT
8074-1143

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Koichi NANIWAE

Conf. unknown

Application No. 10/573,492

Group unknown

Filed March 24, 2006

Examiner unknown

METHOD OF CLEANING TREATMENT AND METHOD
FOR MANUFACTURING SEMICONDUCTOR DEVICE

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

June 27, 2006

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the accompanying document, a copy of which is attached to this statement, is made of record on the enclosed sheet.

A concise explanation of the relevance of this item is that this reference is discussed on pages 3 and 4 of the present specification.

Respectfully submitted,

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PATENT OFFICE
U.S. PATENT

(Use several sheets if necessary)

8074-1143

10/573.492

Koichi NANIWAE

March 24, 2006

unknown

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS									
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FOREIGN PATENT DOCUMENTS

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER:	DATE CONSIDERED
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DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

* Abstract provided for the Examiner's convenience